

Connecting via Winsock to STN

Welcome to STN International! Enter x:x

LOGINID:ssptasmb1637

PASSWORD:

TERMINAL (ENTER 1, 2, 3, OR ?):2

\* \* \* \* \* \* \* \* \* \* \* \* Welcome to STN International \* \* \* \* \* \* \* \* \* \*

NEWS 1 Web Page for STN Seminar Schedule - N. America  
NEWS 2 JAN 02 STN pricing information for 2008 now available  
NEWS 3 JAN 16 CAS patent coverage enhanced to include exemplified prophetic substances  
NEWS 4 JAN 28 USPATFULL, USPAT2, and USPATOLD enhanced with new custom IPC display formats  
NEWS 5 JAN 28 MARPAT searching enhanced  
NEWS 6 JAN 28 USGENE now provides USPTO sequence data within 3 days of publication  
NEWS 7 JAN 28 TOXCENTER enhanced with reloaded MEDLINE segment  
NEWS 8 JAN 28 MEDLINE and LMEDLINE reloaded with enhancements  
NEWS 9 FEB 08 STN Express, Version 8.3, now available  
NEWS 10 FEB 20 PCI now available as a replacement to DPCI  
NEWS 11 FEB 25 IFIREF reloaded with enhancements  
NEWS 12 FEB 25 IMSPRODUCT reloaded with enhancements  
NEWS 13 FEB 29 WPINDEX/WPIDS/WPIX enhanced with ECLA and current U.S. National Patent Classification  
NEWS 14 MAR 31 IFICDB, IFIPAT, and IFIUDB enhanced with new custom IPC display formats  
NEWS 15 MAR 31 CAS REGISTRY enhanced with additional experimental spectra  
NEWS 16 MAR 31 CA/Caplus and CASREACT patent number format for U.S. applications updated  
NEWS 17 MAR 31 LPCI now available as a replacement to LDPCI  
NEWS 18 MAR 31 EMBASE, EMBAL, and LEMBASE reloaded with enhancements  
NEWS 19 APR 04 STN AnaVist, Version 1, to be discontinued  
NEWS 20 APR 15 WPIDS, WPINDEX, and WPIX enhanced with new predefined hit display formats  
NEWS 21 APR 28 EMBASE Controlled Term thesaurus enhanced  
NEWS 22 APR 28 IMSRESEARCH reloaded with enhancements  
NEWS 23 MAY 30 INPAFAMDB now available on STN for patent family searching  
NEWS 24 MAY 30 DGENE, PCTGEN, and USGENE enhanced with new homology sequence search option  
NEWS 25 JUN 06 EPFULL enhanced with 260,000 English abstracts  
NEWS 26 JUN 06 KOREAPAT updated with 41,000 documents

NEWS EXPRESS FEBRUARY 08 CURRENT WINDOWS VERSION IS V8.3,  
AND CURRENT DISCOVER FILE IS DATED 20 FEBRUARY 2008

NEWS HOURS STN Operating Hours Plus Help Desk Availability  
NEWS LOGIN Welcome Banner and News Items  
NEWS IPC8 For general information regarding STN implementation of IPC 8

Enter NEWS followed by the item number or name to see news on that specific topic.

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FILE 'HOME' ENTERED AT 15:58:27 ON 11 JUN 2008

=> file registry  
COST IN U.S. DOLLARS

	SINCE FILE	TOTAL
	ENTRY	SESSION
FULL ESTIMATED COST	0.21	0.21

FILE 'REGISTRY' ENTERED AT 15:59:09 ON 11 JUN 2008  
USE IS SUBJECT TO THE TERMS OF YOUR STN CUSTOMER AGREEMENT.  
PLEASE SEE "HELP USAGETERMS" FOR DETAILS.  
COPYRIGHT (C) 2008 American Chemical Society (ACS)

Property values tagged with IC are from the ZIC/VINITI data file provided by InfoChem.

STRUCTURE FILE UPDATES: 10 JUN 2008 HIGHEST RN 1027136-44-2  
DICTIONARY FILE UPDATES: 10 JUN 2008 HIGHEST RN 1027136-44-2

New CAS Information Use Policies - enter HELP USAGETERMS for details

TSCA INFORMATION NOW CURRENT THROUGH January 9, 2008.

Please note that search-term pricing does apply when conducting SmartSELECT searches.

REGISTRY includes numerically searchable data for experimental and predicted properties as well as tags indicating availability of experimental property data in the original document. For information on property searching in REGISTRY, refer to:

<http://www.cas.org/support/stn/gen/stndoc/properties.html>

=> ...Testing the current file... screen

ENTER SCREEN EXPRESSION OR (END):end

=>  
Uploading C:\Program Files\Stnexp\Queries\10765366\str2d.str



```
chain nodes :  
1 5  
ring/chain nodes :  
2 3 4 11 12  
chain bonds :  
1-2 4-5  
ring/chain bonds :  
2-3 2-11 2-12 3-4  
exact/norm bonds :  
2-3 2-11 2-12 3-4 4-5  
exact bonds :  
1-2  
  
G1:CH3,CF3  
  
Match level :  
1:CLASS 2:CLASS 3:CLASS 4:CLASS 5:CLASS 11:CLASS 12:CLASS
```

L1           STRUCTURE UPLOADED

=> que L1

L2 QUE L1

=> s 11  
SAMPLE SEARCH INITIATED 15:59:32 FILE 'REGISTRY'  
SAMPLE SCREEN SEARCH COMPLETED - 562 TO ITERATE

100.0% PROCESSED 562 ITERATIONS  
SEARCH TIME: 00.00.01

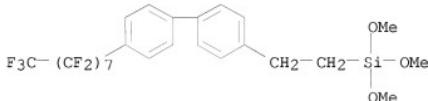
19 ANSWERS

FULL FILE PROJECTIONS: ONLINE \*\*COMPLETE\*\*  
BATCH \*\*COMPLETE\*\*  
PROJECTED ITERATIONS: 9818 TO 12662  
PROJECTED ANSWERS: 119 TO 641

L3 19 SEA SSS SAM L1

=> d scan 1  
'1' IS NOT A VALID FORMAT FOR FILE 'REGISTRY'

L3 19 ANSWERS REGISTRY COPYRIGHT 2008 ACS on STN  
IN 1,1'-Biphenyl, 4-(1,1,2,2,3,3,4,4,5,5,6,6,7,7,8,8,8-heptadecafluorooctyl)-  
4'-(2-(trimethoxysilyl)ethyl)-  
MF C25 H21 F17 O3 Si



\*\*PROPERTY DATA AVAILABLE IN THE 'PROP' FORMAT\*\*

The following are valid formats:

Substance information can be displayed by requesting individual fields or predefined formats. The predefined substance formats are: (RN = CAS Registry Number)

REG - RN  
SAM - Index Name, MF, and structure - no RN  
FIDE - All substance data, except sequence data  
IDE - FIDE, but only 50 names  
SQIDE - IDE, plus sequence data  
SQIDE3 - Same as SQIDE, but 3-letter amino acid codes are used  
SQD - Protein sequence data, includes RN  
SQD3 - Same as SQD, but 3-letter amino acid codes are used  
SQN - Protein sequence name information, includes RN  
  
CALC - Table of calculated properties  
EPROP - Table of experimental properties  
PROP - EPROP and CALC

Any CA File format may be combined with any substance format to obtain CA references citing the substance. The substance formats must be cited first. The CA File predefined formats are:

ABS -- Abstract  
APPS -- Application and Priority Information  
BIB -- CA Accession Number, plus Bibliographic Data  
CAN -- CA Accession Number  
CBIB -- CA Accession Number, plus Bibliographic Data (compressed)  
IND -- Index Data  
IPC -- International Patent Classification  
PATS -- PI, SO  
STD -- BIB, IPC, and NCL

IABS -- ABS, indented, with text labels  
IBIB -- BIB, indented, with text labels  
ISTD -- STD format, indented

OBIB ----- AN, plus Bibliographic Data (original)  
OIBIB ----- OBIB, indented with text labels

SBIB ----- BIB, no citations  
SIBIB ----- IBIB, no citations

The ALL format gives FIDE BIB ABS IND RE, plus sequence data when it is available.

The MAX format is the same as ALL.

The IALL format is the same as ALL with BIB ABS and IND indented, with text labels.

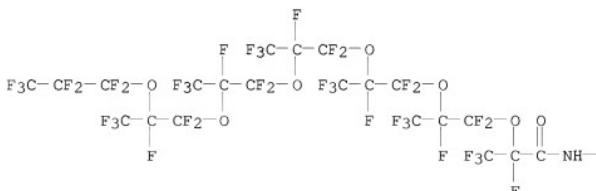
For additional information, please consult the following help messages:

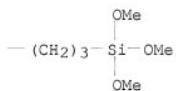
HELP DFIELDS -- To see a complete list of individual display fields.  
HELP FORMATS -- To see detailed descriptions of the predefined formats.  
HOW MANY MORE ANSWERS DO YOU WISH TO SCAN? (1):1

L3 19 ANSWERS REGISTRY COPYRIGHT 2008 ACS on STN  
IN 2-Propenoic acid, 3-(trimethoxysilyl)propyl ester, polymer with  
 $\alpha$ -(dimethyl[2-(trimethoxysilyl)ethyl]silyl)- $\omega$ -(dimethyl[2-(trimethoxysilyl)ethyl]silyl)oxy poly(oxy(dimethylsilylene)),  
(3,3,4,4,5,5,6,6,7,7,8,8,9,9,10,10,10-heptadecafluorodecyl)trimethoxysilane and 2,4,4,5,7,7,8,10,10,11,13,13,14,16,16,17,19,19,20,20,21,21,21-tricosafluoro-2,5,8,11,14,17-hexakis(trifluoromethyl)-N-[3-(trimethoxysilyl)propyl]-3,6,9,12,15,18-hexaoxaheneicosanamide  
MF (C27 H16 F41 N O10 Si . C13 H13 F17 O3 Si . C9 H18 O5 Si . (C2 H6 O Si)n  
C14 H38 O7 Si4)x  
CI PMS

CM 1

PAGE 1-A

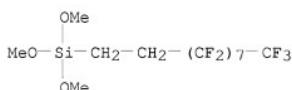




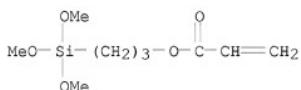
CM 2



CM 3



CM 4



HOW MANY MORE ANSWERS DO YOU WISH TO SCAN? (1):

HOW MANY MORE ANSWERS DO YOU WISH TO SCAN? (1):0

```
=> s 11 ful
FULL SEARCH INITIATED 16:00:06 FILE 'REGISTRY'
FULL SCREEN SEARCH COMPLETED - 10724 TO ITERATE
```

100.0% PROCESSED 10724 ITERATIONS  
 SEARCH TIME: 00.00.01

329 ANSWERS

L4 329 SEA SSS FUL L1

```
=> ....Testing the current file.... screen
ENTER SCREEN EXPRESSION OR (END):end

=> screen 965
L5      SCREEN CREATED
=>
Uploading C:\Program Files\Stnexp\Queries\10765366\str2c.str
```



```
chain nodes :
1 2 3 4 5 6 7
chain bonds :
1-2 2-3 2-6 2-7 3-4 4-5
exact/norm bonds :
4-5
exact bonds :
1-2 2-3 2-6 2-7 3-4
```

```
G1:CH3,CF3
```

```
Match level :
1:CLASS 2:CLASS 3:CLASS 4:CLASS 5:CLASS 6:CLASS 7:CLASS
```

L6 STRUCTURE UPLOADED

=> que L6 AND L5

L7 QUE L6 AND L5

=> s 17 ful

FULL SEARCH INITIATED 16:00:38 FILE 'REGISTRY'  
FULL SCREEN SEARCH COMPLETED - 3302 TO ITERATE

100.0% PROCESSED 3302 ITERATIONS  
SEARCH TIME: 00:00.01

196 ANSWERS

L8 196 SEA SSS FUL L6 AND L5

=> s 14 or 18

L9 525 L4 OR L8

=> ....Testing the current file.... screen

ENTER SCREEN EXPRESSION OR (END):end

=> screen 965

L10 SCREEN CREATED

=>

Uploading C:\Program Files\Stnexp\Queries\10765366\strld.str



chain nodes :

1

ring/chain nodes :

2 3 4 7 8

chain bonds :

1-2

ring/chain bonds :

2-3 2-7 2-8 3-4

exact/norm bonds :

2-3 2-7 2-8 3-4

exact bonds :

1-2

Match level :

1:CLASS 2:CLASS 3:CLASS 4:CLASS 7:CLASS 8:CLASS

L11 STRUCTURE UPLOADED

=> que L11 AND L10

L12 QUE L11 AND L10

=> s 112 ful  
FULL SEARCH INITIATED 16:01:08 FILE 'REGISTRY'  
FULL SCREEN SEARCH COMPLETED - 89633 TO ITERATE

100.0% PROCESSED 89633 ITERATIONS 12873 ANSWERS  
SEARCH TIME: 00.00.01

L13 12873 SEA SSS FUL L11 AND L10

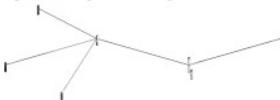
=> ....Testing the current file.... screen

ENTER SCREEN EXPRESSION OR (END):end

=> screen 965

L14 SCREEN CREATED

=>  
Uploading C:\Program Files\Stnexp\Queries\10765366\str1d.str



chain nodes :

1  
ring/chain nodes :

2 3 4 7 8

chain bonds :

1-2

ring/chain bonds :

2-3 2-7 2-8 3-4

exact/norm bonds :

2-3 2-7 2-8 3-4

exact bonds :

1-2

Match level :

1:CLASS 2:CLASS 3:CLASS 4:CLASS 7:CLASS 8:CLASS

L15 STRUCTURE UPLOADED

=> que L15 AND L14

L16 QUE L15 AND L14

=> s 116 ful  
FULL SEARCH INITIATED 16:01:30 FILE 'REGISTRY'  
FULL SCREEN SEARCH COMPLETED - 89633 TO ITERATE

100.0% PROCESSED 89633 ITERATIONS 12873 ANSWERS  
SEARCH TIME: 00.00.01

L17 12873 SEA SSS FUL L15 AND L14

=> s l13 or l17

L18 12873 L13 OR L17

=> s l18 and l9

L19 229 L18 AND L9

=> file caplus

COST IN U.S. DOLLARS

SINCE FILE

TOTAL

FULL ESTIMATED COST

ENTRY

SESSION

713.90

714.11

FILE 'CAPLUS' ENTERED AT 16:02:05 ON 11 JUN 2008

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FILE COVERS 1907 - 11 Jun 2008 VOL 148 ISS 24

FILE LAST UPDATED: 10 Jun 2008 (20080610/ED)

Effective October 17, 2005, revised CAS Information Use Policies apply. They are available for your review at:

<http://www.cas.org/legal/infopolicy.html>

=> s l19  
L20 795 L19

=> dup remove l20

PROCESSING COMPLETED FOR L20

L21 794 DUP REMOVE L20 (1 DUPLICATE REMOVED)

=> s l21 and silicon  
L22 794 S L21  
883161 SILICON  
421 SILICONES  
883305 SILICON  
(SILICON OR SILICONES)  
L23 140 L22 AND SILICON

=> dup remove l23

PROCESSING COMPLETED FOR L23

L24 140 DUP REMOVE L23 (0 DUPLICATES REMOVED)

=> s l24 and (vapor or cvd or pecvd)  
L25 140 S L24  
564157 VAPOR  
74017 VAPORS  
607606 VAPOR  
(VAPOR OR VAPORS)

76827 CVD  
83 CVDS  
76848 CVD  
(CVD OR CVDS)  
8624 PECVD  
L26 25 L25 AND (VAPOR OR CVD OR PECVD)

=> dup remove 126  
PROCESSING COMPLETED FOR L26  
L27 25 DUP REMOVE L26 (0 DUPLICATES REMOVED)

=> d ti 1-25

L27 ANSWER 1 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Layer-by-layer fabrication of broad-band super-hydrophobic antireflection coatings in near-infrared region

L27 ANSWER 2 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Digital magnetofluidic devices and methods

L27 ANSWER 3 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Method of processing a biological and/or chemical sample

L27 ANSWER 4 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Thin organic alignment layers with a batch process for liquid crystal displays

L27 ANSWER 5 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Atmospheric plasma deposition of hydrophobic/oil-repellent coatings with improved durability on glass/ceramic windows

L27 ANSWER 6 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Method for constructing surface enhanced substrate with metal ordered structure

L27 ANSWER 7 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Method for identical dye molecule emitting different color fluorescent light by substrate induction

L27 ANSWER 8 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Surface engineering of poly(dimethylsiloxane) micro fluidic devices using transition metal sol-gel chemistry

L27 ANSWER 9 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Thermal stability of vapor phase deposited self-assembled monolayers for MEMS anti-stiction

L27 ANSWER 10 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Surface modification of silicon and polydimethylsiloxane surfaces with vapor-phase-deposited ultrathin fluorosilane films for biomedical nanodevices

L27 ANSWER 11 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Rain-proof glass windows with a silicon-containing hydrophobic surface of improved durability

L27 ANSWER 12 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Micropatterning of SrBi<sub>2</sub>Ta<sub>209</sub> ferroelectric thin films using a selective deposition technique combined with patterned self-assembled monolayers and liquid-source misted chemical deposition

L27 ANSWER 13 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN

TI Nanoscale patterning of protein using electron beam lithography of organosilane self-assembled monolayers  
L27 ANSWER 14 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Liquid and vapor phase silanes coating for the release of thin film MEMS  
L27 ANSWER 15 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Thin film forming method and thin film forming substance  
L27 ANSWER 16 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Method of coating microelectromechanical devices  
L27 ANSWER 17 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Method and apparatus for manufacturing anti-reflective films  
L27 ANSWER 18 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Vapor pressures of precursors for the CVD of silicon-based films  
L27 ANSWER 19 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Self-assembled monolayer coatings on nanostencils for the reduction of materials adhesion  
L27 ANSWER 20 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Method for making thin film and electronic apparatus  
L27 ANSWER 21 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Formation method of silicon thin film  
L27 ANSWER 22 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Method for providing water-repellent coatings on optical substrates  
L27 ANSWER 23 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Vapor Phase Self-Assembly of Fluorinated Monolayers on Silicon and Germanium Oxide  
L27 ANSWER 24 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Water-repellent fluorine-containing silicon oxide coatings  
L27 ANSWER 25 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
TI Heat- and chemical-resistant organic thin films and their manufacture

=> d bib 1-25

L27 ANSWER 1 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2008:78111 CAPLUS  
DN 148:333398  
TI Layer-by-layer fabrication of broad-band super-hydrophobic antireflection coatings in near-infrared region  
AU Zhang, Lianbin; Li, Yang; Sun, Junqi; Shen, Jiacong  
CS State Key Lab of Supramolecular Structure and Materials, College of Chemistry, Jilin University, Changchun, 130012, Peop. Rep. China  
SO Journal of Colloid and Interface Science (2008), 319(1), 302-308  
CODEN: JCISA5; ISSN: 0021-9797  
PB Elsevier  
DT Journal  
LA English  
RE.CNT 49 THERE ARE 49 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 2 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2007:100213 CAPLUS  
DN 147:355832  
TI Digital magnetofluidic devices and methods  
IN Hernandez, Sonia Melle; Gomez, Ana N.; Picraux, S. Thomas; Gust, John  
Devens; Hayes, Mark; Lindsay, Solitaire; Garcia, Antonio A.; Wang, Joseph;  
Vazquez-Alvarez, Terannie  
PA Arizona Board of Regents for and on Behalf of Arizona State University,  
USA  
SO PCT Int. Appl., 118pp.  
CODEN: PIXXD2  
DT Patent  
LA English  
FAN.CNT 1

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI WO 2007101174	A2	20070907	WO 2007-US62842	20070227
WO 2007101174	A3	20071221		
W: AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, GT, HN, HR, HU, ID, IL, IN, IS, JP, KE, KG, KM, KN, KP, KR, KZ, LA, LC, LK, LR, LS, LT, LU, LV, LY, MA, MD, MG, MK, MN, MW, MX, MY, MZ, NA, NG, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RS, RU, SC, SD, SE, SG, SK, SL, SM, SV, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, ZA, ZM, ZW RW: AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LT, LU, LV, MC, NL, PL, PT, RO, SE, SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG, BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW, AM, AZ, BY, KG, KZ, MD, RU, TJ, TM, AP, EA, EP, OA				
PRAI US 2006-777679P		P 20060227		

L27 ANSWER 3 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2007:933138 CAPLUS  
DN 147:290978  
TI Method of processing a biological and/or chemical sample  
IN Pipper, Juergen; Hsieh, Tseng-Ming; Neuzil, Pavel  
PA Agency for Science, Technology and Research, Singapore  
SO PCT Int. Appl., 67pp.  
CODEN: PIXXD2  
DT Patent  
LA English  
FAN.CNT 1

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI WO 2007094739	A1	20070823	WO 2006-SG29	20060213
W: AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, HR, HU, ID, IL, IN, IS, JP, KE, KG, KM, KN, KP, KR, KZ, LC, LK, LR, LS, LT, LU, LV, LY, MA, MD, MG, MK, MN, MW, MX, MZ, NA, NG, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RU, SC, SD, SE, SG, SK, SL, SM, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, YU, ZA, ZM, ZW RW: AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LT, LU, LV, MC, NL, PL, PT, RO, SE, SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG, BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW, AM, AZ, BY, KG, KZ, MD, RU, TJ, TM				
PRAI WO 2006-SG29		20060213		

RE.CNT 5 THERE ARE 5 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 4 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2007:970042 CAPLUS  
DN 147:288568  
TI Thin organic alignment layers with a batch process for liquid crystal displays  
IN Ong, Hiap L.  
PA Kyoritsu Optronics Co., Ltd., Taiwan  
SO U.S. Pat. Appl. Publ., 16pp., Cont.-in-part of U.S. Ser. No. 227,570.  
CODEN: USXXCO  
DT Patent  
LA English  
FAN.CNT 2

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	US 20070202253	A1	20070830	US 2006-607246	20061201
	US 20070059438	A1	20070315	US 2005-227570	20050915
	CN 101191198	A	20080604	CN 2007-10165733	20071106
PRAI	US 2005-227570	A2	20050915		
	US 2006-607246	A	20061201		

L27 ANSWER 5 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2007:1449167 CAPLUS  
DN 148:83928  
TI Atmospheric plasma deposition of hydrophobic/oil-repellent coatings with improved durability on glass/ceramic windows  
IN Durandeau, Anne; Montigaud, Herve; Abbott, Fabrice; Huignard, Arnaud  
PA Saint-Gobain Glass France, Fr.  
SO Fr. Demande, 28pp.  
CODEN: FRXXBL  
DT Patent  
LA French  
FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	FR 2902422	A1	20071221	FR 2006-52159	20060616
	WO 2007144536	A1	20071221	WO 2007-FR51421	20070612
	W: AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BH, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DO, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, GT, HN, HR, HU, ID, IL, IN, IS, JP, KE, KG, KM, KN, KP, KR, KZ, LA, LC, LK, LR, LS, LT, LU, LY, MA, MD, ME, MG, MK, MN, MW, MX, MY, MZ, NA, NG, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RS, RU, SC, SD, SE, SG, SK, SL, SM, SV, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, ZA, ZM, ZW RW: AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LT, LU, LV, MC, MT, NL, PL, PT, RO, SE, SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG, BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW, AM, AZ, BY, KG, KZ, MD, RU, TJ, TM				

PRAI FR 2006-52159 A 20060616  
RE.CNT 3 THERE ARE 3 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 6 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2007:980718 CAPLUS  
DN 147:376451  
TI Method for constructing surface enhanced substrate with metal ordered structure  
IN Lu, Nan; Yang, Bingjie; Huang, Chunyu; Chi, Lifeng  
PA Jilin University, Peop. Rep. China  
SO Faming Zhuanli Shenqing Gongkai Shuomingshu, 30pp.  
CODEN: CNXXEV  
DT Patent

LA Chinese

FAN.CNT 1

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI CN 101024483	A	20070829	CN 2007-10055453	20070327
PRAI CN 2007-10055453		20070327		

L27 ANSWER 7 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2006:1085199 CAPLUS

DN 146:35674

TI Method for identical dye molecule emitting different color fluorescent light by substrate induction

IN Lu, Nan; Hu, Wei; Hao, Juanyuan; Chi, Lifeng

PA Jilin University, Peop. Rep. China

SO Faming Zhanli Shenqing Gongkai Shuomingshu, 24pp.

CODEN: CNXXEV

DT Patent

LA Chinese

FAN.CNT 1

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI CN 1844300	A	20061011	CN 2006-10016744	20060404
PRAI CN 2006-10016744		20060404		

L27 ANSWER 8 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2006:277375 CAPLUS

DN 144:489687

TI Surface engineering of poly(dimethylsiloxane) micro fluidic devices using transition metal sol-gel chemistry

AU Roman, Gregory T.; Culbertson, Christopher T.

CS Department of Chemistry, Kansas State University, Manhattan, KS, 66506, USA

SO Langmuir (2006), 22(9), 4445-4451

CODEN: LANGD5; ISSN: 0743-7463

PB American Chemical Society

DT Journal

LA English

RE.CNT 86 THERE ARE 86 CITED REFERENCES AVAILABLE FOR THIS RECORD

ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 9 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2006:1341743 CAPLUS

DN 147:475337

TI Thermal stability of vapor phase deposited self-assembled monolayers for MEMS anti-stiction

AU Zhuang, Yan Xin; Hansen, Ole; Knieling, Thomas; Wang, Christian; Rombach, Pirmin; Lang, Walter; Benecke, Wolfgang; Kehlenbeck, Markus; Koblitz, Joern

CS CINE, MIC-Department of Micro and Nanotechnology, Technical University of Denmark, Lyngby, DK-2800, Den.

SO Journal of Micromechanics and Microengineering (2006), 16(11), 2259-2264

CODEN: JMMIEZ; ISSN: 0960-1317

PB Institute of Physics Publishing

DT Journal

LA English

RE.CNT 22 THERE ARE 22 CITED REFERENCES AVAILABLE FOR THIS RECORD

ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 10 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN

AN 2006:641508 CAPLUS

DN 145:183229

TI Surface modification of silicon and polydimethylsiloxane

- surfaces with vapor-phase-deposited ultrathin fluorosilane films  
 for biomedical nanodevices  
 AU Bhushan, Bharat; Hansford, Derek; Lee, Kang Kug  
 CS Nanotribology Laboratory for Information Storage and MEMS/NEMS, The Ohio  
 State University, Columbus, OH, 43202, USA  
 SO Journal of Vacuum Science & Technology, A: Vacuum, Surfaces, and Films  
 (2006), 24(4), 1197-1202  
 CODEN: JVTDAD; ISSN: 0734-2101  
 PB American Institute of Physics  
 DT Journal  
 LA English  
 RE.CNT 10 THERE ARE 10 CITED REFERENCES AVAILABLE FOR THIS RECORD  
 ALL CITATIONS AVAILABLE IN THE RE FORMAT
- L27 ANSWER 11 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
 AN 2005:902015 CAPLUS  
 DN 143:233933  
 TI Rain-proof glass windows with a silicon-containing hydrophobic  
 surface of improved durability  
 IN Duran, Maxime; Huignard, Arnaud  
 PA Saint-Gobain Glass France, Fr.  
 SO Fr. Demande, 32 pp.  
 CODEN: FRXXBL  
 DT Patent  
 LA French  
 FAN.CNT 1
- | PATENT NO.   | KIND | DATE     | APPLICATION NO.  | DATE     |
|--|------|----------|------------------|----------|
| PI FR 2866643  | A1   | 20050826 | FR 2004-50343    | 20040224 |
| FR 2866643   | B1   | 20060526 |                  |          |
| WO 2005084943  | A2   | 20050915 | WO 2005-FR50119  | 20050223 |
| WO 2005084943  | A3   | 20051103 |                  |          |
| W: AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH,<br>CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD,<br>GE, GH, GM, HR, ID, IL, IN, IS, JP, KE, KG, KP, KR, KZ, LC,<br>LK, LR, LS, LT, LU, LV, MA, MD, MG, MK, MN, MW, MX, MZ, NA, NI,<br>NO, NZ, OM, PG, PH, PL, PT, RO, RU, SC, SD, SE, SG, SK, SL, SM,<br>SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, YU, ZA, ZM, ZW<br>RW: BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW, AM,<br>AZ, BY, KG, KZ, MD, RU, TJ, TM, AT, BE, BG, CH, CY, CZ, DE, DK,<br>EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LT, LU, MC, NL, PL, PT,<br>RO, SE, SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML,<br>MR, NE, SN, TD, TG |      |          |                  |          |
| EP 1720808   | A2   | 20061115 | EP 2005-728106   | 20050223 |
| R: AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE,<br>IS, IT, LI, LT, LU, MC, NL, PL, PT, RO, SE, SI, SK, TR   |      |          |                  |          |
| CN 1946646   | A    | 20070411 | CN 2005-80012900 | 20050223 |
| BR 2005007935  | A    | 20070717 | BR 2005-7935     | 20050223 |
| JP 2007523776  | T    | 20070823 | JP 2007-500274   | 20050223 |
| IN 2006KN02325   | A    | 20070525 | IN 2006-KN2325   | 20060817 |
| MX 2006PA09574   | A    | 20061107 | MX 2006-PA9574   | 20060823 |
| PRAI FR 2004-50343   | A    | 20040224 |                  |          |
| WO 2005-FR50119  | W    | 20050223 |                  |          |
- RE.CNT 2 THERE ARE 2 CITED REFERENCES AVAILABLE FOR THIS RECORD  
 ALL CITATIONS AVAILABLE IN THE RE FORMAT
- L27 ANSWER 12 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
 AN 2005:410625 CAPLUS  
 DN 143:88377  
 TI Micropatterning of SrBi<sub>2</sub>Ta<sub>209</sub> ferroelectric thin films using a selective  
 deposition technique combined with patterned self-assembled monolayers and  
 liquid-source misted chemical deposition

AU Takakuwa, Atsushi; Ishida, Masaya; Shimoda, Tatsuya  
CS Technology Platform Research Center, SEIKO EPSON Corporation, Nagano,  
399-0293, Japan  
SO Japanese Journal of Applied Physics, Part 1: Regular Papers, Short Notes &  
Review Papers (2005), 44(4A), 1897-1900  
CODEN: JAPNDE  
PB Japan Society of Applied Physics  
DT Journal  
LA English  
RE.CNT 8 THERE ARE 8 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 13 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2005:702603 CAPLUS  
DN 144:208350  
TI Nanoscale patterning of protein using electron beam lithography of  
organosilane self-assembled monolayers  
AU Zhang, Guo-Jun; Tanii, Takashi; Zako, Tamotsu; Hosaka, Takumi; Miyake,  
Takeo; Kanari, Yuzo; Funatsu, Takashi; Ohdomari, Iwao  
CS Nanotechnology Research Center and Institute of Biomedical Engineering,  
Waseda University, Tokyo, 162-0041, Japan  
SO Small (2005), 1(8-9), 833-837  
CODEN: SMALBC; ISSN: 1613-6810  
PB Wiley-VCH Verlag GmbH & Co. KGaA  
DT Journal  
LA English  
RE.CNT 22 THERE ARE 22 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 14 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2006:143210 CAPLUS  
DN 144:499593  
TI Liquid and vapor phase silanes coating for the release of thin  
film MEMS  
AU Parvais, B.; Pallandre, A.; Jonas, A. M.; Raskin, J.-P.  
CS Research Center in Micro and Nanoscopic Materials and Electronic Devices  
(CERMIN), Universite catholique de Louvain, Louvain-la-Neuve, B-1348,  
Belg.  
SO IEEE Trans. Device Mater. Reliab. (2005), 5(2), 250-254  
CODEN: ITDMA2; ISSN: 1530-4388  
URL: <http://ieeexplore.ieee.org/iel5/7298/31396/01458741.pdf?isnumber=31396&prod=JNL&arnumber=1458741&arSt=+250&ared=+254&arAuthor=Parvais%2C+B.%3B+Pallandre%2C+A.%3B+Jonas%2C+A.M.%3B+Raskin%2C+J.-P.>  
PB Institute of Electrical and Electronics Engineers  
DT Journal; (online computer file)  
LA English  
RE.CNT 18 THERE ARE 18 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 15 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2004:1060574 CAPLUS  
DN 142:40141  
TI Thin film forming method and thin film forming substance  
IN Kudo, Ichiro; Saito, Atsushi; Arita, Hiroaki  
PA Konica Minolta Holdings, Inc., Japan  
SO U.S. Pat. Appl. Publ., 32 pp.  
CODEN: USXXCO  
DT Patent  
LA English  
FAN.CNT 1

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
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PI	US 20040247886	A1	20041209	US 2004-858704	20040601
JP	2004360039	A	20041224	JP 2003-162032	20030606
JP	2005023381	A	20050127	JP 2003-191025	20030703
	WO 2004108984	A1	20041216	WO 2004-JP7860	20040531
	W: AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, HR, HU, ID, IL, IN, IS, KE, KG, KP, KR, KZ, LC, LK, LR, LS, LT, LU, LV, MA, MD, MG, MK, MN, MW, MX, MZ, NA, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RU, SC, SD, SE, SG, SK, SL, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, YU, ZA, ZM, ZW RW: BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW, AM, AZ, BY, KG, KZ, MD, RU, TJ, TM, AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IT, LU, MC, NL, PL, PT, RO, SE, SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG				
	EP 1643002	A1	20060405	EP 2004-735520	20040531
	R: AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT, IE, SI, LT, LV, FI, RO, MK, CY, AL, TR, BG, CZ, EE, HU, PL, SK, HR				
	CN 1798865	A	20060705	CN 2004-80015446	20040531
PRAI	JP 2003-162032	A	20030606		
	JP 2003-191025	A	20030703		
	WO 2004-JP7860	W	20040531		

L27 ANSWER 16 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
 AN 2004:162231 CAPLUS

DN 140:227524  
 TI Method of coating microelectromechanical devices  
 IN Yang, Zhihao  
 PA Eastman Kodak Company, USA  
 SO U.S. Pat. Appl. Publ., 7 pp.  
 CODEN: USXXCO

DT Patent  
 LA English  
 FAN.CNT 1

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
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PI US 20040037956	A1	20040226	US 2002-225846	20020822
US 6808745	B2	20041026		
EP 1416064	A2	20040506	EP 2003-77499	20030811
EP 1416064	A3	20050615		
EP 1416064	B1	20080507		
R: AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT, IE, SI, LT, LV, FI, RO, MK, CY, AL, TR, BG, CZ, EE, HU, SK				
JP 2004084073	A	20040318	JP 2003-298568	20030822
PRAI US 2002-225846	A	20020822		
RE.CNT 7 THERE ARE 7 CITED REFERENCES AVAILABLE FOR THIS RECORD ALL CITATIONS AVAILABLE IN THE RE FORMAT				

L27 ANSWER 17 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
 AN 2004:198553 CAPLUS

DN 140:236678  
 TI Method and apparatus for manufacturing anti-reflective films  
 IN Tanaka, Takeshi  
 PA Konica Minolta Holdings Inc., Japan  
 SO Jpn. Kokai Tokkyo Koho, 40 pp.  
 CODEN: JKXXAF

DT Patent  
 LA Japanese  
 FAN.CNT 1

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
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PI JP 2004075738	A	20040311	JP 2002-234607	20020812

PRAI JP 2002-234607

20020812

L27 ANSWER 18 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2004:157226 CAPLUS  
DN 140:383314  
TI Vapor pressures of precursors for the CVD of silicon-based films  
AU Alcott, Gregory R.; van de Sanden, Richard M. C. M.; Kondic, Sascha; Linden, Joannes L.  
CS Department of Applied Physics, Eindhoven University of Technology, Eindhoven, 5600 MB, Neth.  
SO Chemical Vapor Deposition (2004), 10(1), 20-22  
CODEN: CVDEFX; ISSN: 0948-1907  
PB Wiley-VCH Verlag GmbH & Co. KGaA  
DT Journal  
LA English  
RE.CNT 6 THERE ARE 6 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 19 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2003:256239 CAPLUS  
DN 139:37976  
TI Self-assembled monolayer coatings on nanostencils for the reduction of materials adhesion  
AU Kolbel, Marius; Tjerkstra, R. Willem; Kim, Gyuman; Brugger, Jurgen; van Rijn, Cees J. M.; Nijdam, Wietze; Huskens, Jurriaan; Reinhoudt, David N.  
CS Laboratory of Supramolecular Chemistry and Technology MESA+ Research Institute, University of Twente, Enschede, NL-7500 AE, Neth.  
SO Advanced Functional Materials (2003), 13(3), 219-224  
CODEN: AFMDC6; ISSN: 1616-301X  
PB Wiley-VCH Verlag GmbH & Co. KGaA  
DT Journal  
LA English  
RE.CNT 17 THERE ARE 17 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 20 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2002:638152 CAPLUS  
DN 137:177507  
TI Method for making thin film and electronic apparatus  
IN Furusawa, Masahiro; Shimoda, Tatsuya  
PA Seiko Epson Corporation, Japan  
SO U.S. Pat. Appl. Publ., 13 pp.  
CODEN: USXXCO  
DT Patent  
LA English  
PAN.CNT 1

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI US 20020114887	A1	20020822	US 2001-26635	20011227
US 6780465	B2	20040824		
JP 2002275629	A	20020925	JP 2001-398535	20011227
PRAI JP 2000-403229	A	20001228		

RE.CNT 5 THERE ARE 5 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 21 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 2002:539411 CAPLUS  
DN 137:101690  
TI Formation method of silicon thin film  
IN Furusawa, Masahiro; Miyashita, Satoru; Yudasaka, Kazuo; Shimoda, Tatsuya; Yokoyama, Yasuaki; Matsuki, Yasuo; Takeuchi, Yasumasa

PA Seiko Epson Corp., Japan; JSR Ltd.  
SO Jpn. Kokai Tokkyo Koho, 7 pp.  
CODEN: JKXXAF

DT Patent  
LA Japanese  
FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	JP 2002203794	A	20020719	JP 2000-402809	20001228
	JP 3745959	B2	20060215		
	US 20030087110	A1	20030508	US 2001-28712	20011228
	US 6846513	B2	20050125		
PRAI	JP 2000-402809	A	20001228		
OS	MARPAT 137:101690				

L27 ANSWER 22 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 1999:783781 CAPLUS  
DN 132:37023

TI Method for providing water-repellent coatings on optical substrates  
IN Anthes, Uwe; Dombrowski, Reiner  
PA Merck Patent G.m.b.H., Germany  
SO Eur. Pat. Appl., 8 pp.  
CODEN: EPXXDW

DT Patent  
LA German  
FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	EP 962511	A1	19991208	EP 1999-110077	19990522
	EP 962511	B1	20051116		
	R: AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT, IE, SI, LT, LV, FI, RO				
	DE 19825100	A1	19991216	DE 1998-19825100	19980605
	ES 2252887	T3	20060516	ES 1999-110077	19990522
	JP 2000080331	A	20000321	JP 1999-153778	19990601
	JP 3549440	B2	20040804		
	KR 2000005904	A	20000125	KR 1999-20580	19990604
	US 6296793	B1	20011002	US 1999-325796	19990604
	US 20010033893	A1	20011025	US 2001-892712	20010628
PRAI	DE 1998-19825100	A	19980605		
	US 1999-325796	A3	19990604		
OS	MARPAT 132:37023				

RE.CNT 6 THERE ARE 6 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 23 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN  
AN 1997:178996 CAPLUS  
DN 126:298032  
OREF 126:57613a,57616a  
TI Vapor Phase Self-Assembly of Fluorinated Monolayers on  
Silicon and Germanium Oxide  
AU Hoffmann, Patrick W.; Stelzle, Martin; Rabolt, John F.  
CS IBM Almaden Research Center, San Jose, CA, 95120, USA  
SO Langmuir (1997), 13(7), 1877-1880  
CODEN: LANGD5; ISSN: 0743-7463

PB American Chemical Society  
DT Journal  
LA English

RE.CNT 21 THERE ARE 21 CITED REFERENCES AVAILABLE FOR THIS RECORD  
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 24 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN

AN 1995:330786 CAPLUS

DN 122:108850

OREF 122:20441a,20444a

TI Water-repellent fluorine-containing silicon oxide coatings

IN Sumi, Toshio; Matsuda, Atsunori; Ogino, Etsuo; Soejima, Ayako

PA Nippon Sheet Glass Co Ltd, Japan

SO Jpn. Kokai Tokkyo Koho, 7 pp.

CODEN: JKXXAF

DT Patent

LA Japanese

FAN.CNT 1

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI JP 06228755	A	19940816	JP 1993-16332	19930203
PRAI JP 1993-16332		19930203		

L27 ANSWER 25 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN

AN 1994:109608 CAPLUS

DN 120:109608

OREF 120:19339a,19342a

TI Heat- and chemical-resistant organic thin films and their manufacture

IN Morikawa, Juko; Kasanuki, Juji; Yanagisawa, Yoshihiro; Matsuda, Hiroshi

PA Canon Kk, Japan

SO Jpn. Kokai Tokkyo Koho, 8 pp.

CODEN: JKXXAF

DT Patent

LA Japanese

FAN.CNT 1

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI JP 05220887	A	19930831	JP 1992-28417	19920214
JP 3025091	B2	20000327		
PRAI JP 1992-28417		19920214		

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ALL L# QUERIES AND ANSWER SETS ARE DELETED AT LOGOFF

LOGOFF? (Y)/N/HOLD:y

COST IN U.S. DOLLARS

SINCE FILE

TOTAL

ENTRY SESSION

FULL ESTIMATED COST

48.69

762.80

STN INTERNATIONAL LOGOFF AT 16:03:30 ON 11 JUN 2008